# Task 4.6 Development of a generic CDR for automated XAS Beamlines

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HELMHOLTZ SPITZENFORSCHUNG FÜR GROSSE HERAUSFORDERUNGEN

# **Overview**

- > Task 4.6 within CREMLINplus
- > Current Status
- > Future Perspectives





# **Task 4.6 within CREMLINplus**



# Task 4.6 within CREMLINplus

- > WP4 Collaboration with USSR
- Task 4.6 Scientific case, beamlines and experimental stations: definition of perspective techniques for a 4<sup>th</sup> generation source
- > D4.1 Report on the scientific case and the conceptual design of a scattering/diffraction beamline due in January 2021
- D4.7 and M24 Report on the scientific case and the conceptual development of a prototype spectroscopy beamline due in January 2022
- > D4.14 and M48 Report on the scientific case and conceptual development of beamlines and experimental stations due in January 2024



#### Comparison of nanoprobe beamlines

- > from existing and planned 4<sup>th</sup> generation synchrotron rings 4GSR
- > comparing main components and distances

					-	
	ID16B, ESRF-EBS	ID01, ESRF-EBS	NanoMAX, MAX IV	ISN-ID19, APS-U	3DMN-34ID, APS-U	CHEX-28ID, APS-U
aperture	30	_	-	27	27	27
mirrors	30	_	25	29	30	26+34
aperture	-	—	—	30	47	-
mono	35	33	28	32	54	35
focusing	_	_	_	35	_	50
SSA	40	100	51	55 + 64		50
aperture	164	_	_	_	_	_
focusing	165	119	84/94	220	65	63

Table 1: Overview of the distances of beam shaping elements at different nanoprobe beamlines of 4GSR.





Table 2: Beamline parameters of existing nanoprobe beamlines of 4CSR. DCM – double crystal monochromator, CCM – channel cut monochromator, KB mirrors – Kirkpatrick-Baez mirrors, FZP – Fresnel zone plates, CRL – compound refractive lenses, NF – nanofocusing, WBM – white beam mirror, H – horizontal, V – vertical

parameter	unit	ID16B, ESRF-EBS [18]	ID01, ESRF- EBS [19, 20]	NanoMAX, MAX IV [21, 22]	ISN-19ID, APS-U [23, 24]	3DMN-34ID, APS-U [23, 24]	CHEX-28ID, B, APS-U [23, 24]	new beamline for USSR
Ring								
electron beam energy	(GeV)	6.037	6.037	3	6	6	6	6
electron beam current	(A)	0.2	0.2	0.25	0.2	0.2	0.2	0.1
dist. to sample	(m)	165	118	94	67	65	220	100
Undulator								
undulator type		in-vacuum	revolver	in-vacuum	revolver	planar	planar	in-vac.
undulator length	(m)	2.5	1.6	1.5	4.6	2.1	1.3	4
period	(mm)	26	27/35	18	21/25	28	19	23
k value	()	N/A	N/A	1.95	$K_y = 1.94$	2.46	2.29 N/A	2.12
minimal gap	(mm)	6.5	11	4.0	N/A	N/A	N/A	6
energy range	(keV)	570	6 24	530	530	530	15 60	5 40
Monochromator								
optical elements		double WBM	-	H & V focusing mirrors	-	flat H mirror	collimators	-
monochromator		V diffracting DCM, Si(111)	CCM & DCM, Si(111)	H diffracting DCM, Si(111)	H deflecting DCM, Si(111)	DCM	H DCM	DCM, Si(111)
offset	(mm)	12.5	N/Á	13.3	N/A	1.1	N/A	10.0
End Station								
secondary focusing		KB mirrors	FZP	KB mirrors or FZP	NF mirrors	KB mirrors	CRL	CRL or mirrors
min. beam size flux	$_{(ph/s)}^{(nm)}$	$\begin{array}{c} 50\\ 1\times 10^{12a} \end{array}$	$\begin{array}{c} 35 \\ 1 \times 10^{9b} \end{array}$	KB: 300, FZP: 40 $1 \times 10^{12c}$	${5 \times 10^{12c}}$	37 N/A	$\begin{array}{c} 800\\ 4\times10^{13c} \end{array}$	$\begin{array}{c} 50\\ 3\times10^{13d} \end{array}$

<sup>a</sup> 17.5 keV, <sup>b</sup> 8 keV, <sup>c</sup> 10 keV, <sup>d</sup> 20 keV





This project has received funding from the European Union's Horizon 2020 research and innovation programme under grant agreement No. 871072.

## Choosing an appropriate undulator

- > 5 keV to 40 keV
- > nanoprobe → highest brilliance
- > available straight section: 5 m
- in-vacuum undulator, effective length of 4 m
- > design recommended by M. Tischer, DESY:
  - min. gap: 6 mm
  - magnetic field: 0.987 T
  - period length: 23 mm
  - periods: 174
  - k-value: 2.12

# X-Ray Tracing calculations of the undulator





## **Choosing focusing elements**

- Compound Refractive Lenses (CRL), Fresnel Zone Plates (FZP) or Kirkpatrick Baez (KB) mirrors?
- here: CRLs simple handling, "rare" energy changes
- > 2D Be lenses, radius 0.05 mm
- large working distance of 0.6 m for extensive sample environments
- optionally combined with a secondary source CRL (SSA at 77 m)



X-Ray Tracing calculations of the

1 set of CRL,  $E = 20 \,\mathrm{keV}$ , sample position





#### 1 set of CRL, E = 20 keV, $0.22 \times 0.07 \, \mu \text{m}^2$



#### 1 set of CRL, $E = 60 \text{ keV}, 197 \times 197 \text{ }\mu\text{m}^2$





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#### 1 set of CRL, E = 60 keV, pinhole, $4.8 \times 4.8 \,\mu\text{m}^2$



2 sets of CRL,  $E = 20 \text{ keV}, 0.45 \times 0.37 \,\mu\text{m}^2$ 

### Comparison of spectroscopy beamlines

- > from existing and planned 4<sup>th</sup> generation synchrotron rings 4GSR
- > comparing main components and distances

		Polar 4-ID B [27]	XPCS 8-ID E [27]	Balder <sup>a</sup> [28, 29]	ID24 EDXAS_L [30]	ID26, EH1 [31, 32]
	aperture WBM/HRM monochromator aperture aperture	27.0 $2 \times 28.5$ 30.0 31.1 47.3	$27.1 \\ 28.0 + 30.6 \\ 33.7 \\ - \\ 51.3$	26.5 + 31.5 28.0 31.0	${ m N/A}\ 28.5+31.0\ 55.0^{b}\ N/A\ N/A\ N/A$	29.7 33.4 34.2
focusing	toroid mirrors KB mirrors transfocators	$\begin{array}{r} 48.0 + 50.0 \\ 61.0 \\ 59.3 \end{array}$	55.3 $52.0$	31.5 	$\begin{array}{r}55.5\\28.5+31.0\\-\end{array}$	$37.2+39.1 \\ -$
	attenuators aperture aperture sample	54.1 53.7 59.4 61.3	N/A 54.8 55.9 56.3	N/A 32.0 - 46.0	N/A N/A N/A 55.6	41.9 42.0 - 43.0





## Comparison of spectroscopy beamlines

- > from existing and planned 4<sup>th</sup> generation synchrotron rings 4GSR
- > comparing main components and distances

		EMA [33, 34]	QUATI [35]	P64 [36, 37]	P65 [38]
	aperture WBM/HRM monochromator aperture aperture	N/A 2 × 33.3 <sup>c</sup> 28.5 N/A N/A	N/A 15.0 + 30.0 24 N/A N/A	$\begin{array}{c} 44.8 + 37.1 \\ 58.7 + 60.1 \\ 56.6 \\ - \end{array}$	49.0 50.0 + 53.0 51.5 –
focusing	toroid mirrors KB mirrors transfocators	44.5 + 96.0	30		
	attenuators aperture aperture sample	45, 97 - - 98	N/A N/A - 45	N/A 87 - 87.2	N/A 59 N/A 60



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parameter	unit	Polar 4-ID, APS-U [27]	XPCS 8-ID, APS-U [27]	Balder, MAX IV [28, 29]	ID24 EDXAS_L, EBS-ESRF [30]	ID26, EBS-ESRF [31, 32]
Ring						
electron beam energy electron beam current	(GeV) (A)	6 0.2	6 0.2	3 0.25	6.037 0.2	6.037 0.2
Undulator						
undulator type undulator length period k value minimal gap	(m) (mm)	2 in-line SCAPE <sup>a</sup> $2 \times 1.3$ 35 + 35 N/A N/A	2 in-line revolver 4.6 21/25 1.29/1.90 N/A	in-vacuum, tapered 2.0 50 9 5.5	4 in-line, 'tapered' $\approx 3 \times 1.5$ 27 + 27 + 27/32 + 32 N/A e.e. 11.0/11.7/12.5	3 in-line $3 \times 1.6$ 35 + 35 + 35 2.45 11.2
energy range	(keV)	2.8 to 27	8 to 25	2.4 to 40	5 to 28	2 to 25
Monochromator						
optical elements		WBM (Si, Pt, Rh)	WBM (Si, Cr, Pt, Rh)	WBM (Si, Ir)	KB-V = WBM (Si, Pt, Rh)	WBM (Si, Pt, Pd)
monochromator		H DCM, Si(111), $LN_2$ cooled	H DCM, $Si(111)$ and $Si(113)$ , $LN_2$ cooled	DCM, $Si(111)$ and $Si(113)$ , $LN_2$ cooled	polychromator, Si(111), Laue geometry	DCM, $Si(111)$ and $Si(113)$ , $LN_2$ cooled
offset	(mm)	N/A	15	10 to 32	N/A	25
End Station						
no. end stations dist. source to sample	(m)	2 61.3/73.3	2 56.3/67.5	1 46.0	$\frac{2}{55.6/64.7}$	$2 \\ 43.0/54.6$
focusing elements		transfocators, KB mirrors, toroidal mirrors	transfocators, KB mirrors	toroidal mirror	KB mirrors	bendable KB mirrors
beam size flux	$(\mu m^2)$ (ph/s)	34 × 4 N/A	0.3  imes 0.3 N/A	$100 \times 100 \\ 1 \times 10^{13b}$	$\begin{array}{l} 4\times 4 \\ 4\times 10^{13c} \end{array}$	$\begin{array}{l} 100\times 50\\ 5\times 10^{13d} \end{array}$
diffractometer		double tilt Eulerian cradle	double tilt Eulerian cradle	1 axis	breadboard	breadboard
detectors etc.		2D fluorescence D, polarization A, Raman S	N/A	Raman S, mass S, X-ray emission S, Lytle D, PIPS D, SDD	2D FReLoN CCD, 1D Hamamatsu CCD, XH Ge microstrip	photo diodes, hard X-ray emission S tender X-ray emission S, SDD



parameter	$\operatorname{unit}$	EMA, Sirius [33, 34]	QUATI, Sirius [35]	P64, PETRA III [36, 37]	P65, PETRA III [38]	new beamline for USSR
Ring						
electron beam energy	(GeV)	3	3	6	6	6
electron beam current	(A)	0.1	0.1	0.1	0.1	0.2
Undulator						
undulator type		in-vacuum	dipole source	??	mini-undulator	revolver
undulator length	(m)	1.2	N/A	2	0.39	4
period	(mm)	20	N/A	32.8	32.8	27
k value		N/A	N/A	2.7	2.6	2.12
minimal gap	(mm)	22	N/A	9.5	10	6
energy range	(keV)	2.7 to 30	4.5 to 35	4 to 44	4 to 44	4 to 39
Monochromator						
optical elements		HRM (Si, Pt, Rh)	WBM (Si, Pt, Rh)	WBM (Si, Pt, Rh)	WBM (Si, Pt, Rh)	-
monochromator		DCM, Si(111) and Si(220), V bounce, fixed exit	DCM, $Si(111)$ and $Si(311)$ , $LN_2$ cooled	CCM and DCM, Si(111), Si(311), LN <sub>2</sub> cooled	DCM, $Si(111)$ and $Si(311)$ , $H_2O$ cooled	
offset	(mm)	0	N/A	21	N/A	0
End Station						
no. end stations		2	2	1	1	
dist. source to sample	(m)	45.5/98	45.5	87.2	N/A	70?
focusing elements		KB mirrors	toroidal mirror (Pt, Rh)	mirrors (Si, Rh)	-	
beam size	$(\mu m^2)$	$1 \times 0.4$	$10 \times 5$	$150 \times 50$	$500 \times 1000$	0
flux	(ph/s)	$1 \times 10^{12e}$	$1 \times 10^{10e}$	$1 \times 10^{13}$ f	$2 \times 10^{12f}$	$5 \times 10^{13g}$
diffractometer		6+2 circles	breadboard	breadboard	breadboard	??
detectors etc.		2D, Raman-S, photodiodes, ion chamber, fluo D	Raman-S	fluorescence D, transmission D, ion chamber, dispersive von-Hamos S	ion chamber, HPGe D, Si-PIPS <sup>h</sup> diodes, fluo D	
$e - 20  \text{keV}, \qquad f - 9$	keV,	g – experimental value	es, $h$ – Passivated	Implanted Planar Silicon		



## Choosing an appropriate undulator

- > 5 keV to 40 keV
- > highest brilliance → penetrate sample environments AND minimize exposure time (increase time resolution)
- using well established ESRF design (55 models listed)
- complementing revolver, in-air undulators, effective length of 2.5 m
  - analyzing groups of undulators with period below and above 32 mm
  - U23 (ID 22\_01)
  - U35 (ID 03\_02)

#### X-Ray Tracing calculations





#### **Choosing optical elements**

- > avoid energy dependent monochromator offset: 2 sets of channel-cut monochromators additional benefit: sharpening of beam profile while almost no additional loss of intensity
- > focusing with KB mirrors (non-dispersive)
  - Si with Rh and Pt coating
  - determining KB size (minimizing cutting-off the beam):  $500 \times 30 \text{ mm}$  and  $400 \times 30 \text{ mm}$

#### X-Ray Tracing calculations





# **Current Status**



## **Changes towards EURIZON**

- > WP4 Synchrotrons
- Task 4.6 Development of a generic Conceptual Design Report for automated X-Ray Absorption Spectroscopy Beamlines
- > D4.22 Report on the 1<sup>st</sup> International Workshop due in January 2023
- M59 Input collection finalized due in June 2023
- > D4.23 Completion of the generic CDR for a fully automated XAS beamline due in December 2023
- > D4.24 Report on the 2<sup>nd</sup> International Workshop due in January 2024



# **Current progress within EURIZON**

### > Oct. 2022:

- starting to organize the workshop
- cooperation with managers of XAS beamlines at DESY
- dedicated session within the XAS satellite workshop at the DESY Users' Meeting (23 – 27 January 2023)
- Nov. 2022: gaining overview of relevant aspects (automation, XAS, in-situ, ...)
- > Dec. 2022: choosing topics and inviting speakers
- Jan. 2023: performing workshop including 6 speakers and more than 70 participants online and in-person

SATELLITE WORKSHOP - Photon Science



X-Ray Absorption Spectroscopy today and perspectives for future PETRA III and IV beamlines Thursday, 26. January 2023, Bldg.3 BAH+#1

Organizers: W. Caliebe, E. Welter, M. Nentwich (DESY)

PROGRAMME				
	Beamline Automation			
14:45	Automatization of synchrotron experiments - present and future	Alexander Schökel		
15:05	SECOP - the Sample Environment Communication Protocol	Klaus Kiefer (Via Zoom)		
15:25	TBD	Peter Weidler		
15:45	XAS reference database under DAPHNE4NFDI	Sebastian Paripsa		
16:05	Relevanz von Automatisierung in der Industrie	Bernd Hinrichsen		
16:25	TBD	Janis Timoshenko		
16:45	Discussion			
17:00	End of Meeting			



# **Future Perspectives**



# **Future Perspectives**

- > evaluation of 1<sup>st</sup> workshop
- > identifying critical topics and issues
- > detailed investigations (M59, due in June 2023)
- > performing xrt calculations to beamline details (yet to be defined)
- > writing CDR (D4.23, due in December 2023)
- > preparing the 2<sup>nd</sup> workshop (presenting CDR)
- report on 2<sup>nd</sup> workshop (D4.24, due in January 2024)



# Conclusion

- > CDR for nanobeam diffraction/scattering beamline
  - comprehensive comparison of existing/ planned beamlines at 4GSR
  - including xrt model of the beamline for adaption
- > CDR for prototype spectroscopy beamline
  - comprehensive comparison of existing/ planned beamlines at 4GSR
  - detailed calculations on the design of the KB mirrors
  - including xrt model of the beamline for adaption
- > 1<sup>st</sup> workshop was held successfully



# **Thanks to**



#### EURIZON for financial support



#### DESY Oliver Seeck Dmitri V. Novikov



#### ESRF Michael Krisch



You for your attention





This project has received funding from the European Union's Horizon 2020 research and innovation programme under grant agreement No. 871072.